INFORMATION DISCLOSURE CITATION IN AN APPLICATION (PTO-1449)	ATTY. DOCKET NO. 005920 USA/MTCG/PCTRL/JW	SERIAL NO. 09/943,383
	APPLICANT SHANMUGASUNDRAM et al.	
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U.S. PATENT DOCUMENTS

EXAMINER'S INITIALS	PATENT NO.	DATE	NAME	CLASS	SUBCLASS	FILING DATE

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EXAMINER (signature)	DATE CONSIDERED April 10, 2006

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OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)

(initials)	January 24, 2005. International Preliminary Examination Report from PCT Application No. PCT/US02/19117.

EXAMINER _Will D. Cl_

DATE CONSIDERED _April 10, 2006_

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